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THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re patent application of

Art Unit 1763

Seung-un KIM, et al.

Examiner: S. Macarthur

Serial No. 10/800,735

*Confirmation No. 1171*

Filed: March 16, 2004

For: APPARATUS AND METHOD FOR SUPPLYING CHEMICALS  
IN CHEMICAL MECHANICAL POLISHING SYSTEMS

**AMENDMENT UNDER 37 C.F.R. §1.111**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, Va. 22313-1450

Sir:

**INTRODUCTORY COMMENTS**

In response to the Office action mailed September 8, 2004, the following amendments and remarks are respectfully submitted in connection with the above-identified application:

**Amendments to the Claims** are reflected in a listing of claims, which begins on page 2 of this paper.

**Remarks** begin on page 5 of this paper.